

BEOL-Compatible On-Chip DC-DC Converters

Sunbin Deng, Jungyoun Kwak, Junmo Lee,
Shimeng Yu, Suman Datta

Georgia Institute of Technology

June 6, 2024

Outline of Presentation

Power Delivery Challenges in Heterogenous 3D (H3D) Integrated Circuits

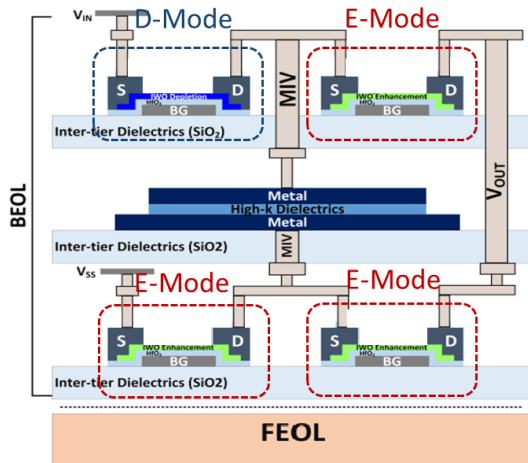
High-Efficiency On-Chip DC-DC Voltage Converters

Back-End-of-Line Compatible On-Chip Components

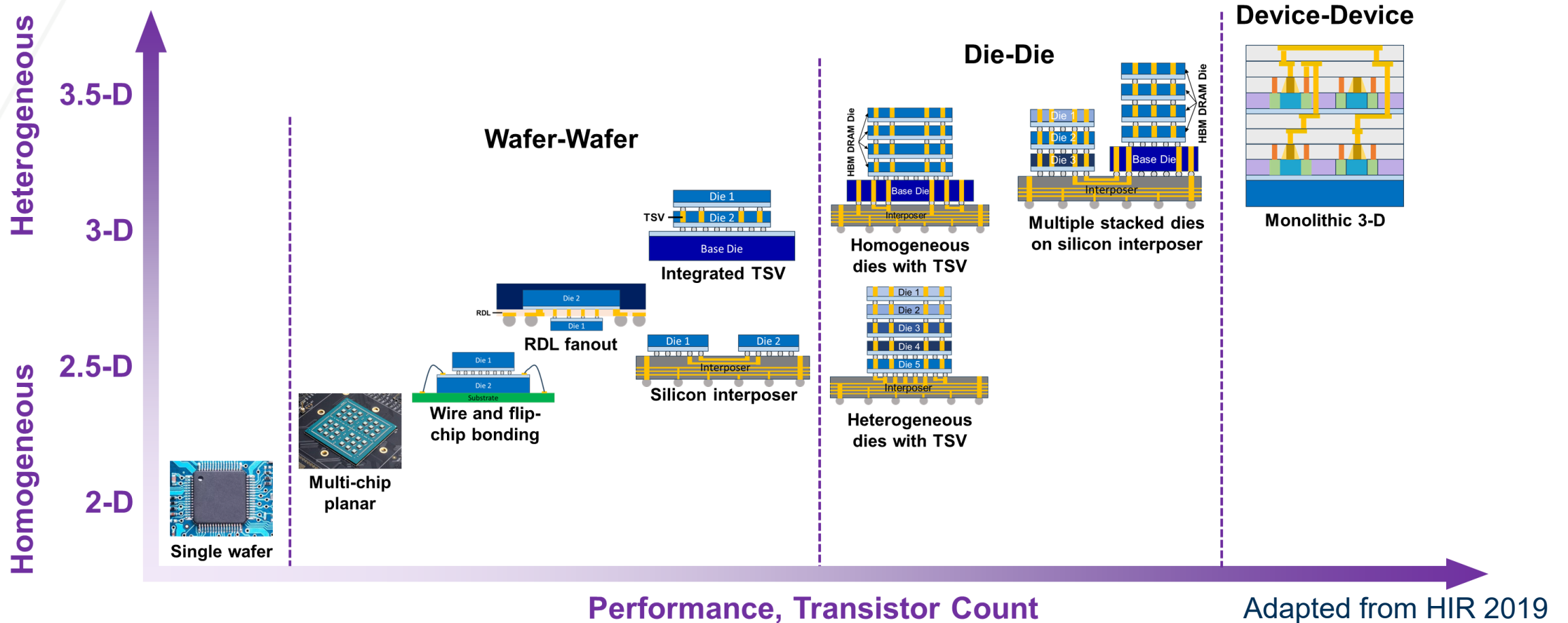
- Amorphous Oxide Semiconductor (AOS) Power Transistors
- Enhancement- and Depletion-Mode AOS Power Transistors
- High-Density Capacitors with High Breakdown Voltage

On-Chip DC-DC Converter Performance

Summary



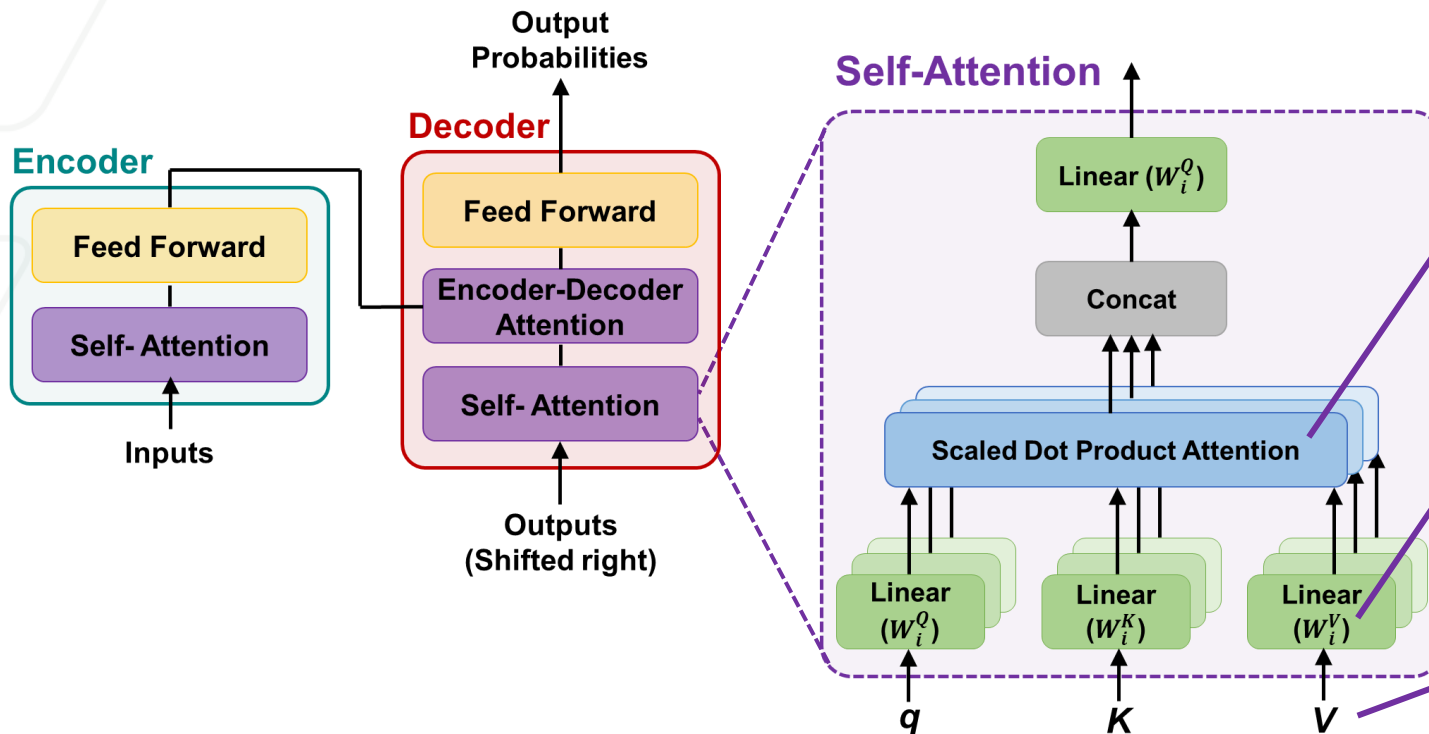
Heterogenous Integrated Circuits



- With a variety of chiplets seamlessly integrated, heterogenous ICs enable system performance scaling.

Example: Transformer Accelerator

Transformer architecture



Technology mapping

- Compute unit (for attention, feedforward, etc.)
 - Leading-edge logic node
- Weight memory (for pre-trained weight storage)
 - Infrequent write operations
 - Non-volatile memory
- Global buffer (for attentional caches, etc.)
 - Frequent write operations
 - Lower write time & energy
 - Higher endurance
 - Higher memory density



176B



280B



340B

PanGu- Σ

1.085T

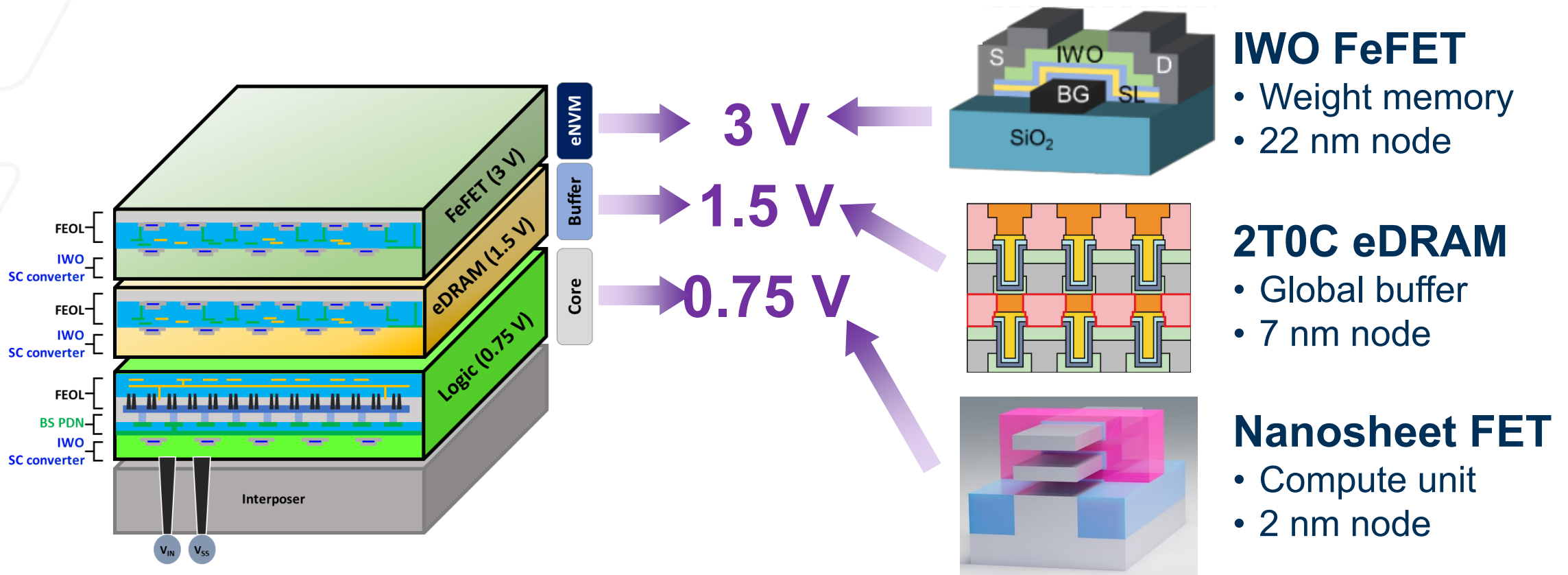


1.7T

of model parameters

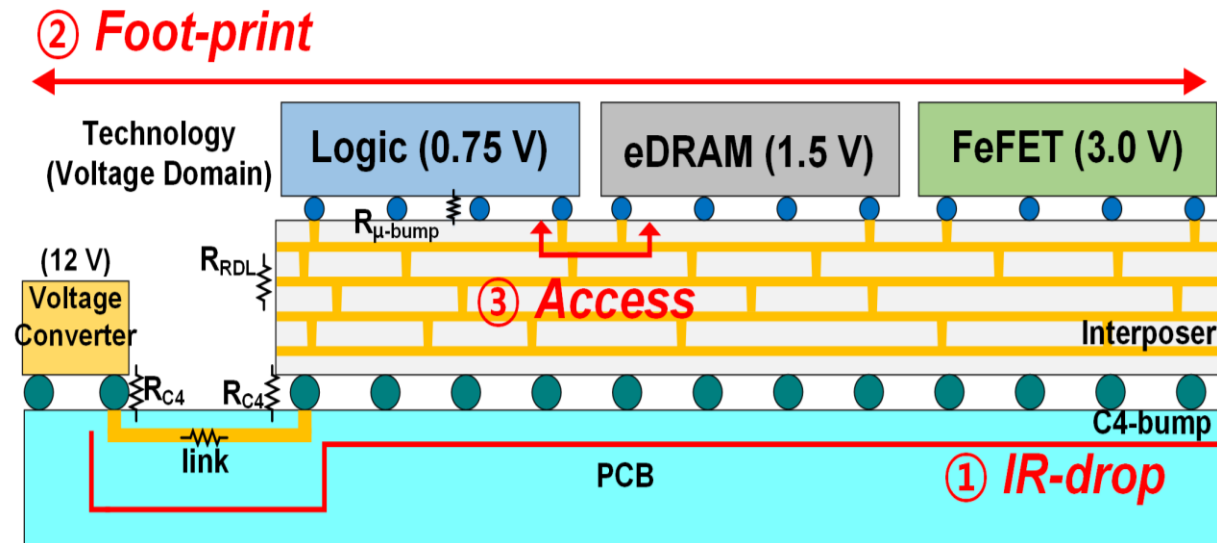
Multiple Voltage Domains in Heterogenous ICs

Multi-Tier Stacked Transformer Accelerator



➤ In heterogenous ICs, different functional tiers may adopt various technology nodes, requiring multiple voltage domains.

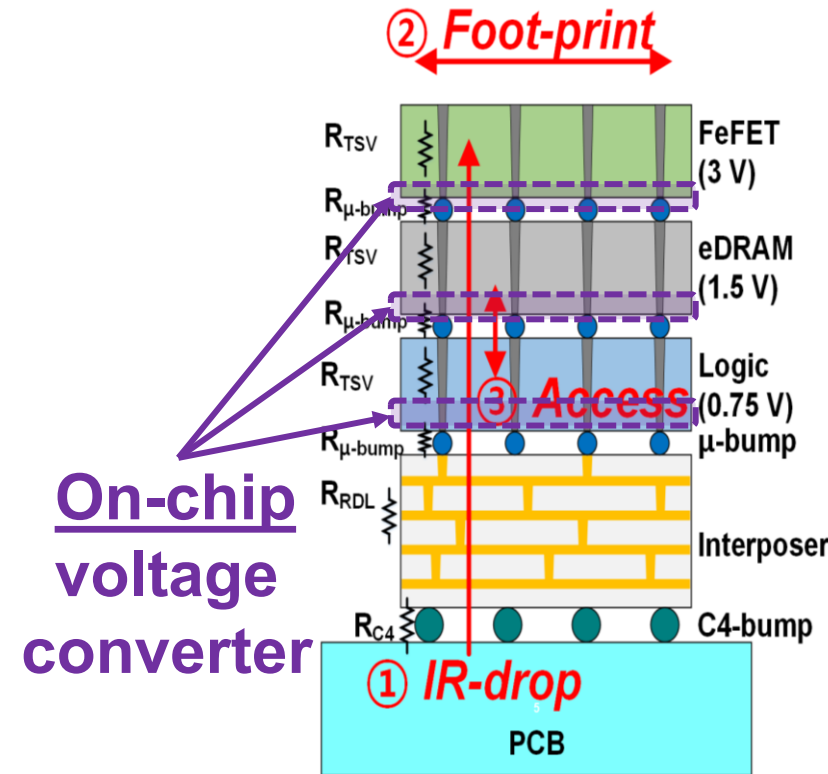
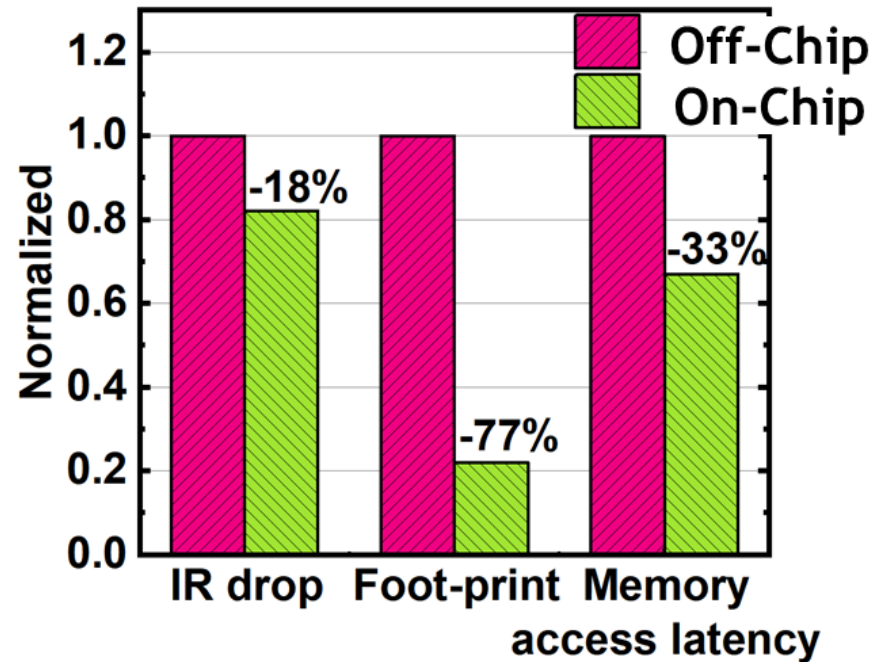
Power Delivery Challenges in Heterogenous ICs



In heterogenous ICs (with **multiple supply voltage domains**):

- ❖ Increased power density demands cause $>10\%$ IR drops and routing losses
- ❖ Off-chip voltage converters increase package footprint
- ❖ Long inter-tier signal length ($>100 \mu\text{m}$) rises data access latency

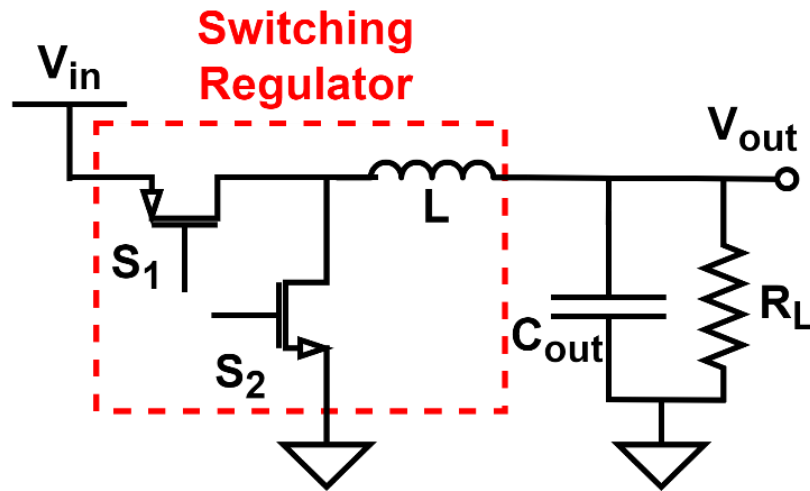
H3D ICs with On-Chip Voltage Converters



- Heterogenous 3D (H3D) architecture with on-chip voltage converters (at least from input 12V to 0.75V) in each tier provides a reduction in IR drop, area, and memory access latency.

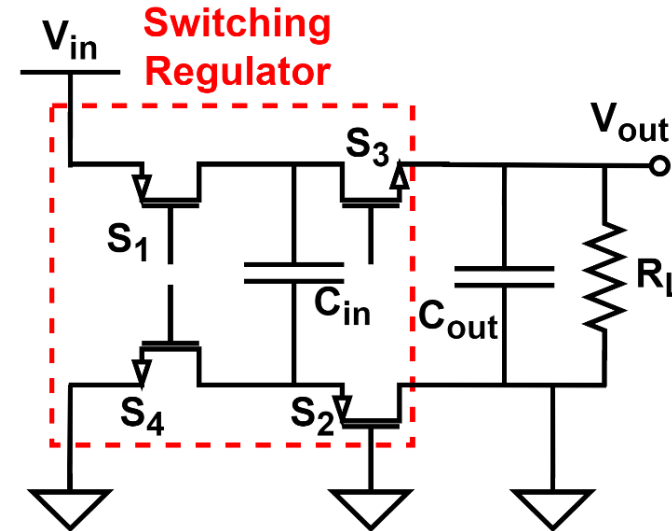
On-chip DC-DC Converter Options

Switched-Inductor



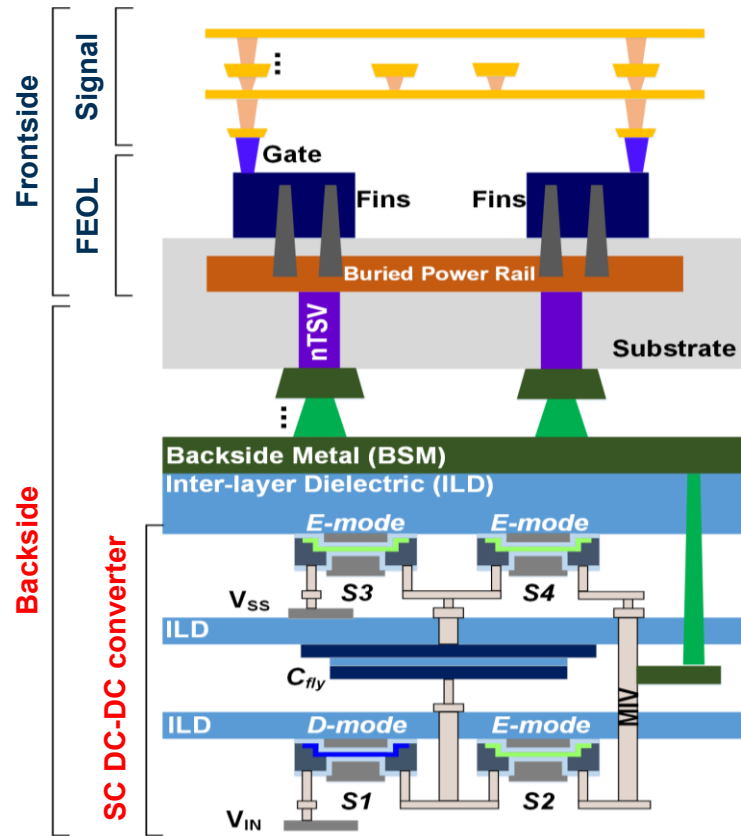
- Pros: high efficiency across a wide range of output voltages (off-chip)
- Cons: large area
increased fab cost & complexity
degraded performance (on-chip)

Switched-Capacitor (SC)

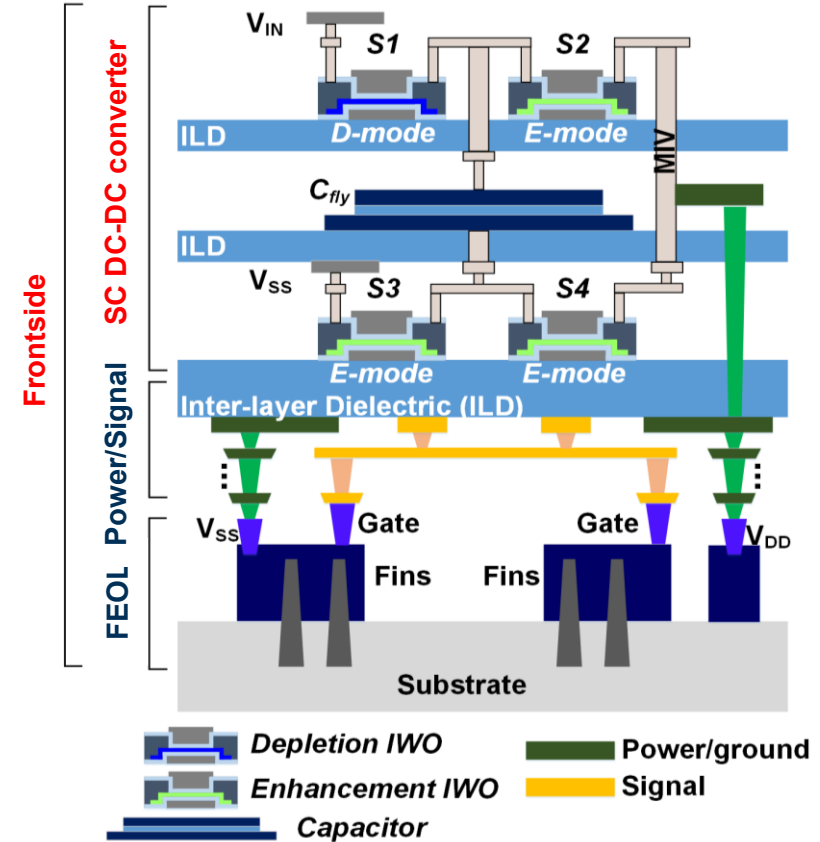


- Pros: CMOS Compatible
Lower intrinsic loss
- Cons: Efficiency vs. conversion ratio
(determined by topology)

Feasible M3D Integration for SC DC-DC Converters

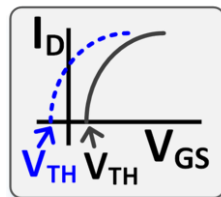
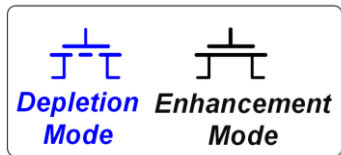
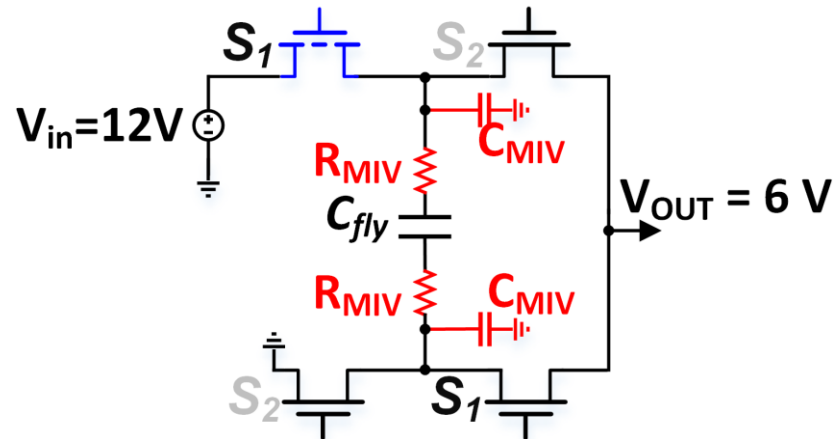


OR



- Monolithic 3D (M3D) integration can further improve power density and area efficiency of SC DC-DC converters in either backside or frontside BEOL.

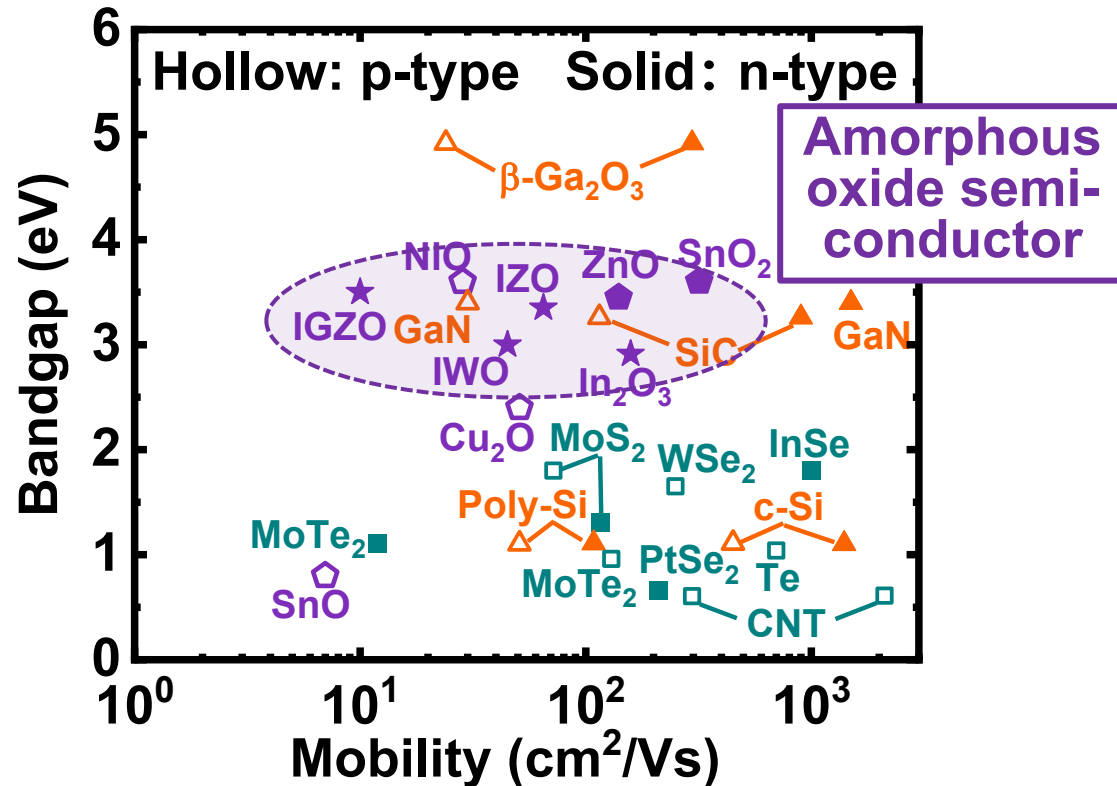
Technology Requirement



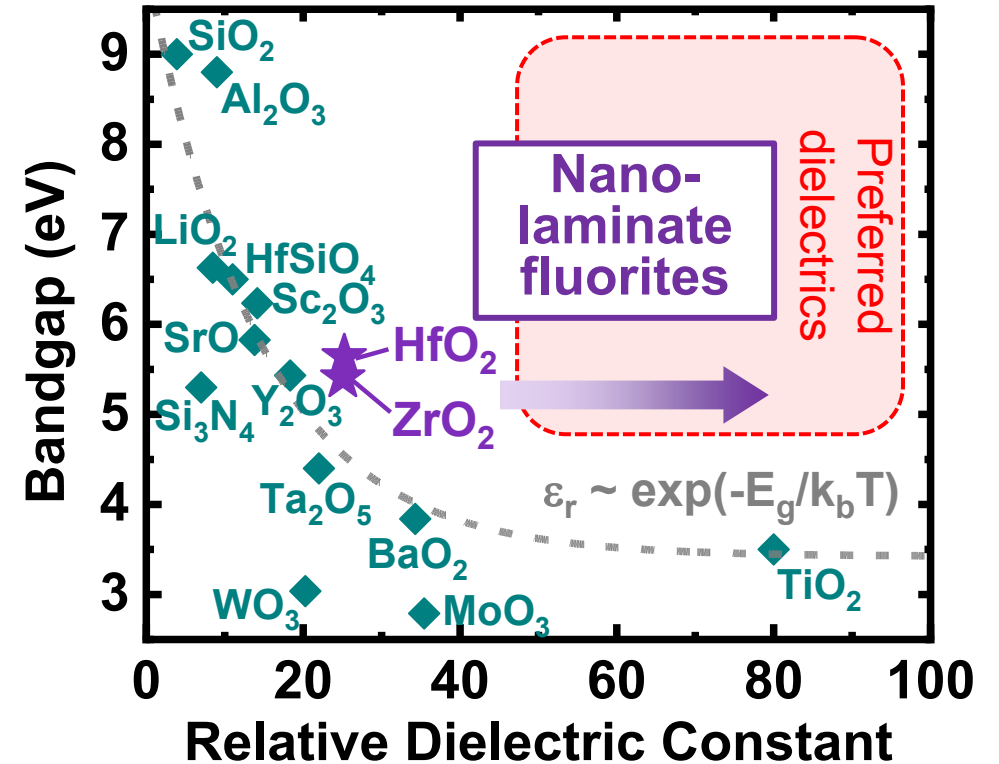
Category	Parameter	Target
On-chip SC DC-DC converters	Voltage conversion	12 V to 6 V
	Power density	1 W/mm ²
	peak efficiency	84%
	On-resistance	14 mΩ·mm ²
BEOL-compatible power <u>FETs</u>	Breakdown	>12 V
	Switching freq.	100 MHz
	Enhancement & depletion mode?	Yes
BEOL-compatible flying <u>capacitors</u>	Breakdown	>6 V
	Capacitance density	400 fF/um ²
	Leakage density	50 pA/mm ²

Materials Candidates for Device Components at BEOL

Power FETs at BEOL



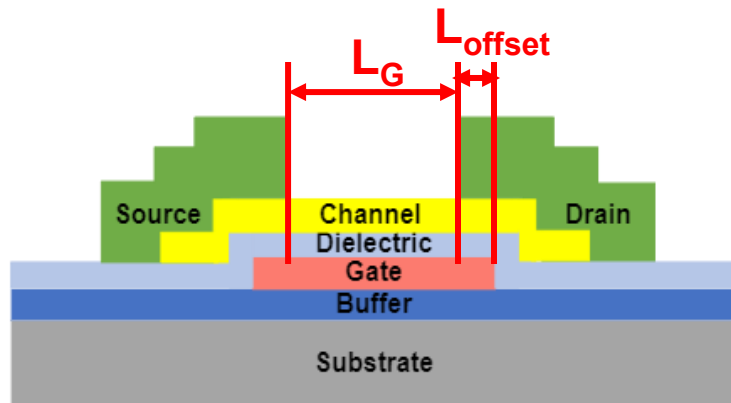
Flying Capacitors at BEOL



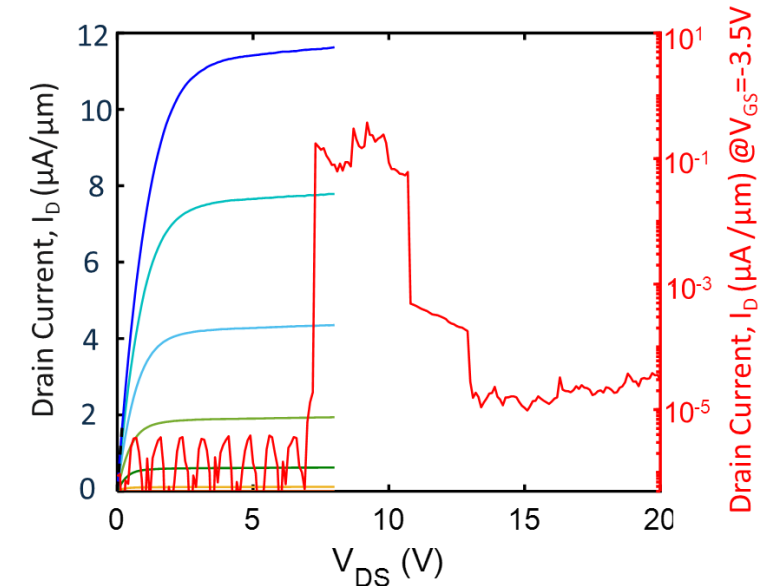
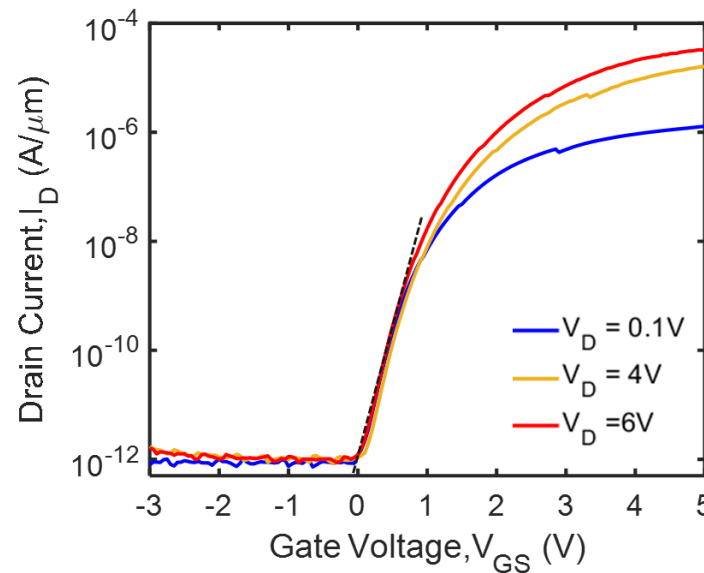
- Amorphous oxide semiconductors for power switches and nanolaminate fluorites for flying capacitors are promising candidates.

IWO MOSFET with G-D Overlap (Conventional)

Conventional FET with G-D Overlap

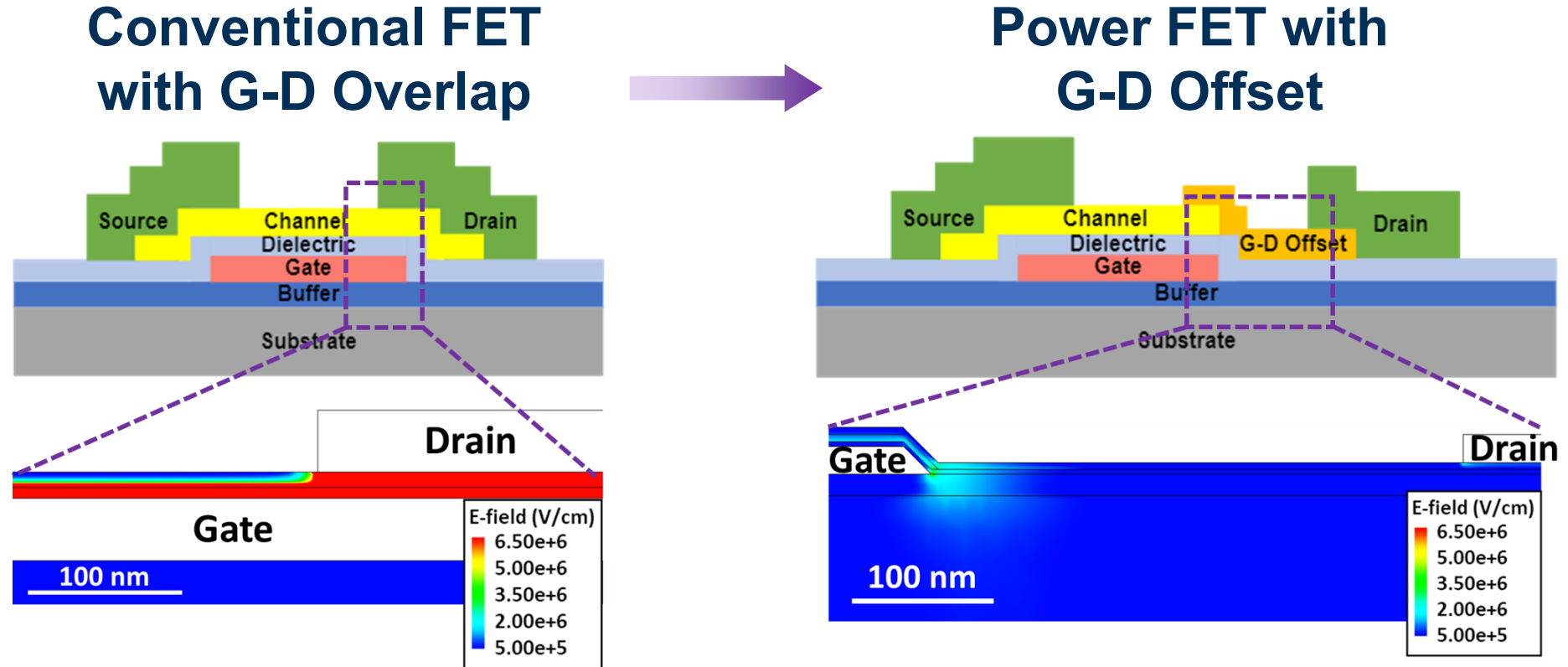


$W/L_G = 10 \mu\text{m}/500 \text{ nm}$, $L_{\text{offset}} = -300 \text{ nm}$



- Device fabrication max temperature is below 300°C .
- Off-state drain breakdown voltage (V_{BD}) in the conventional IWO FETs with G-D overlap is ~ 7 V.

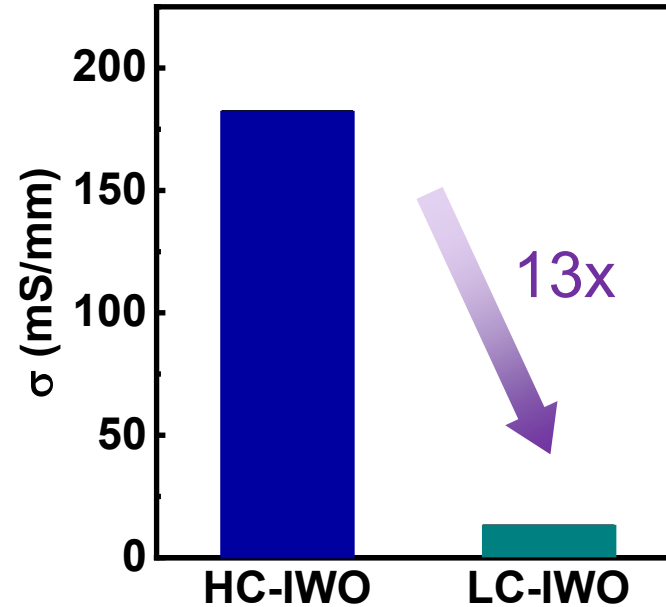
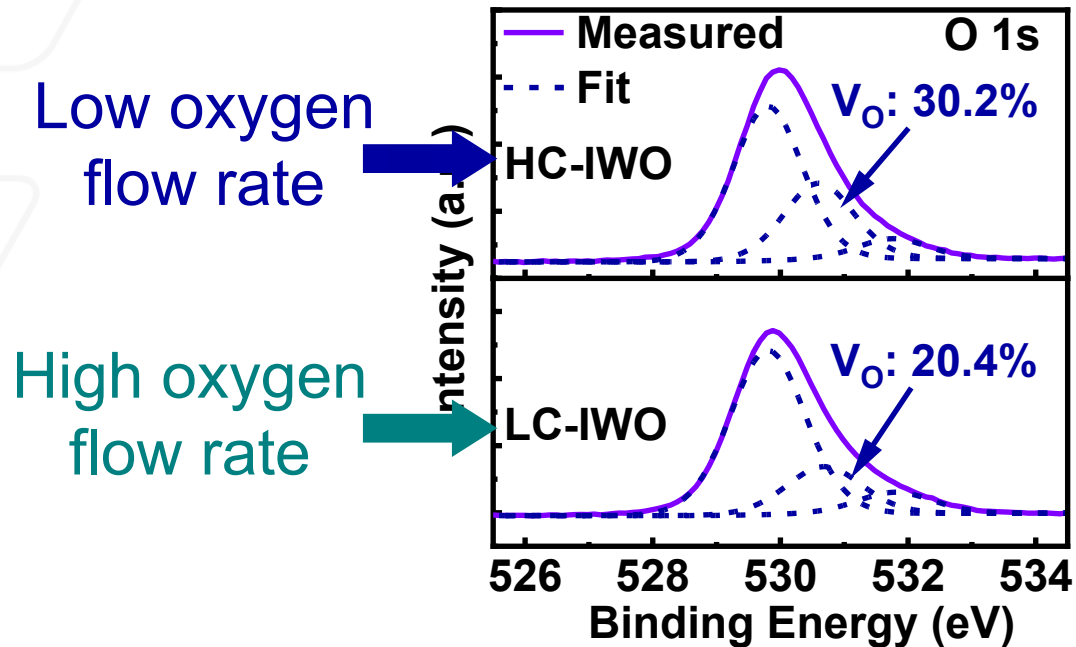
IWO Power FETs with G-D Offset



- Peak electric field along channel length is reduced by 12.7x in the power FETs with G-D offset compared to the conventional MOSFETs.

IWO Conductivity Modulation for E- & D-mode Power FETs

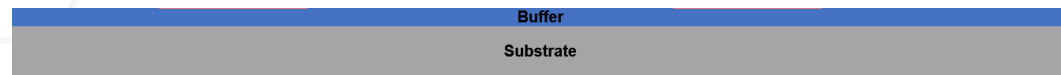
O 1s XPS spectra



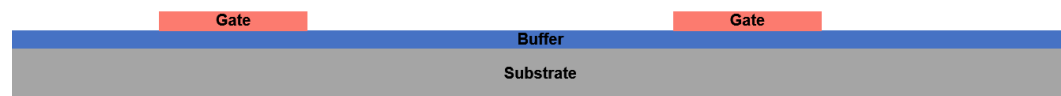
LC: Low-Conductivity
HC: High-Conductivity

- Key strategy: IWO conductivity (and device V_{TH}) can be modulated by oxygen flow rate in IWO deposition.

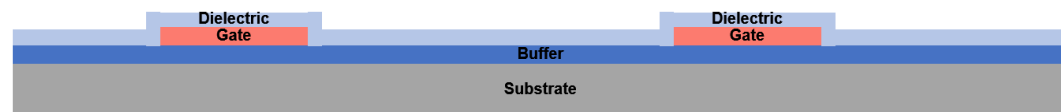
E- & D-mode IWO Power FET Process Flow



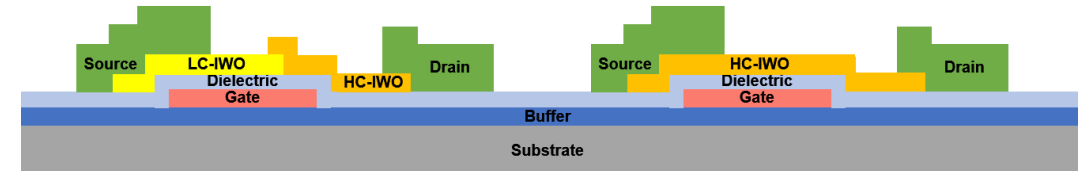
1. Buffer layer (90 nm SiO₂ + 15 nm HfO₂) dep.



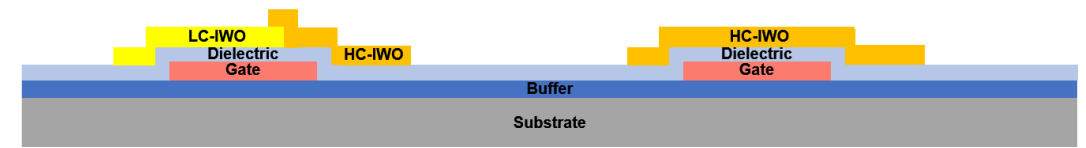
2. Gate electrode (25 nm Pd) dep. & pat.



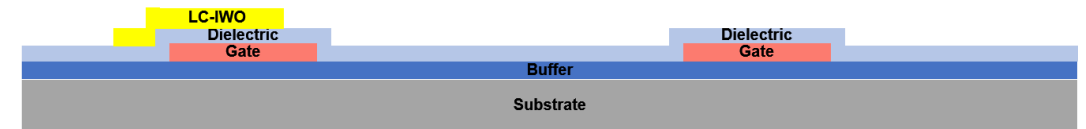
3. Gate insulator (35 nm HfO₂, PEALD, 250 °C) dep.



6. Source/drain contact (40 nm Pd) dep. & pat.

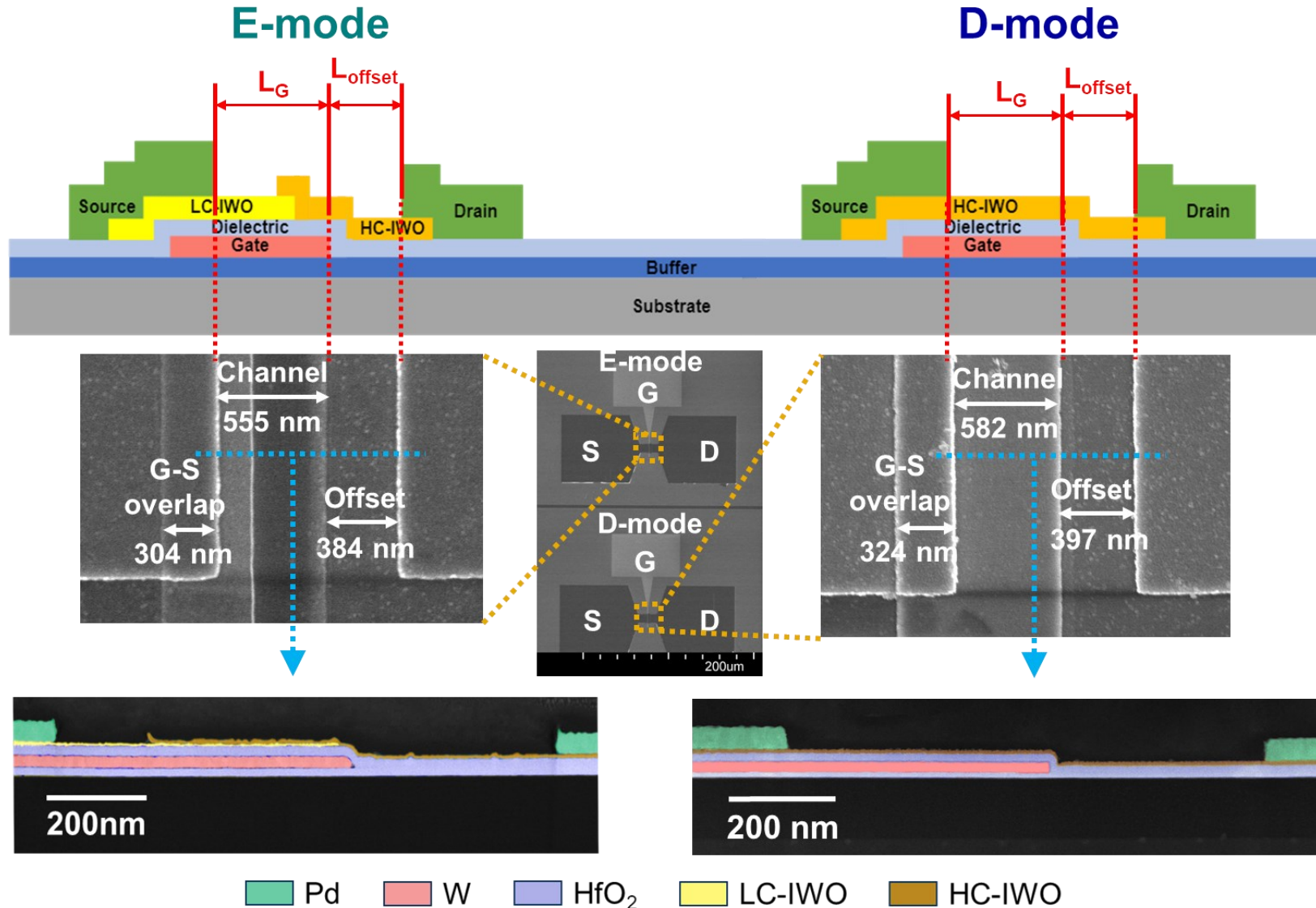


5. **HC-IWO** dep. & pat. for **D-mode channel & offset region** (8 nm, 0.6 sccm O₂ for sputtering)



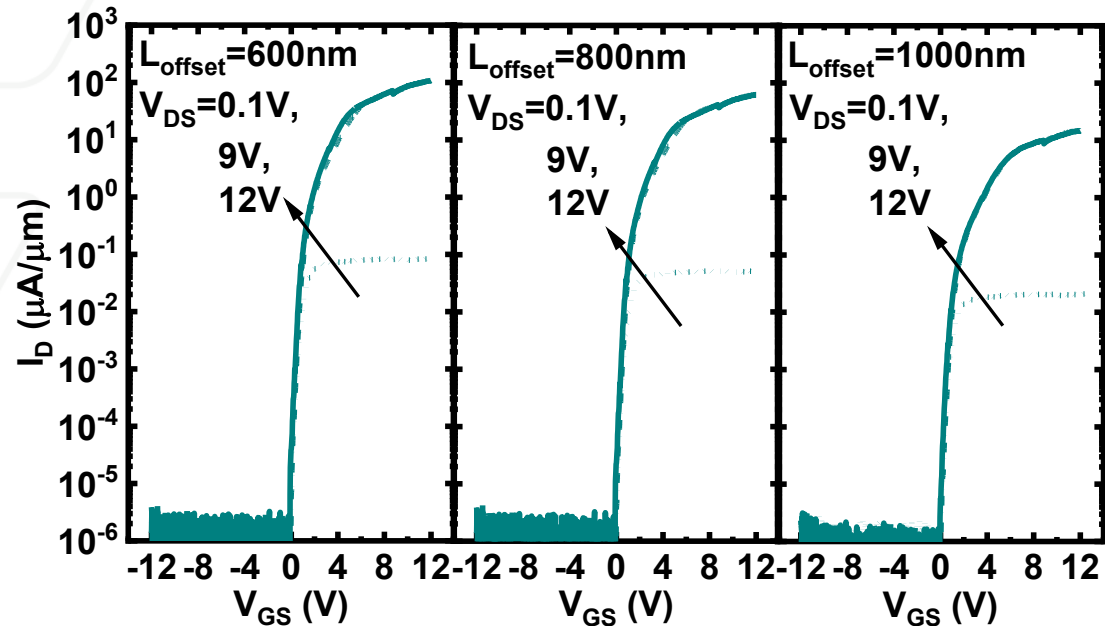
4. **LC-IWO** dep. & pat. for **E-mode channel** (5 nm, 6 sccm O₂ for sputtering)

E- & D-mode IWO Power FET Co-integration

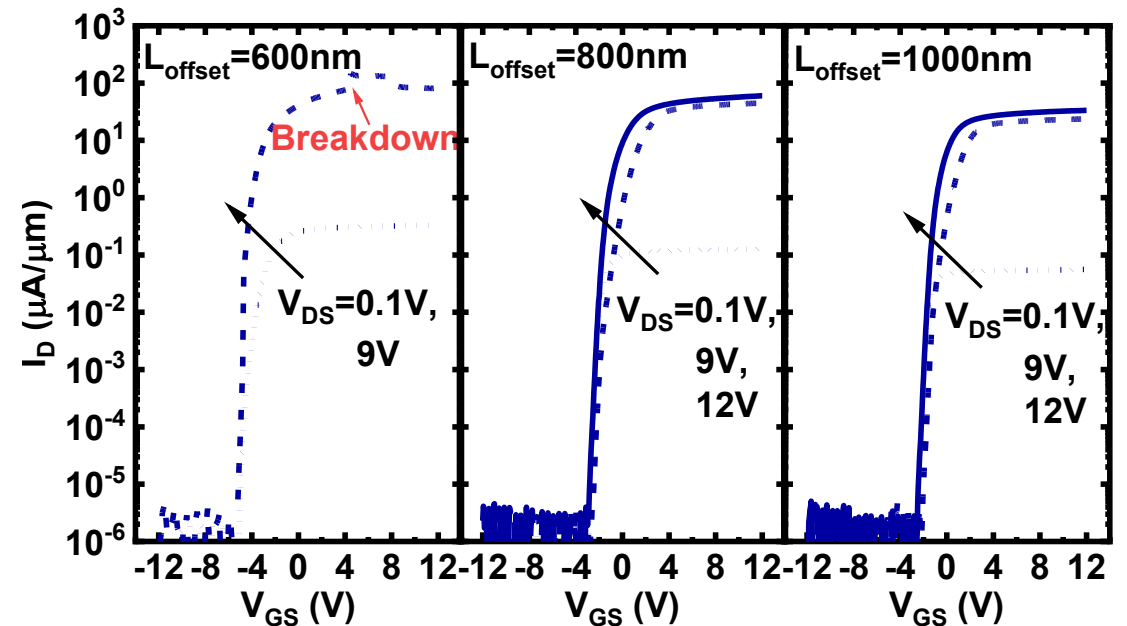


Transfer Characteristics

E-mode ($L_G = 600$ nm)

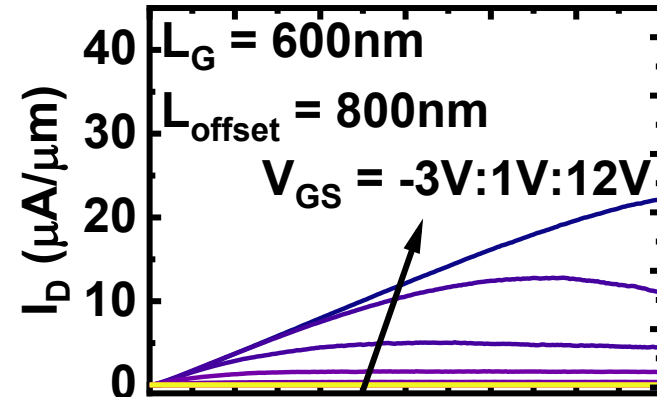
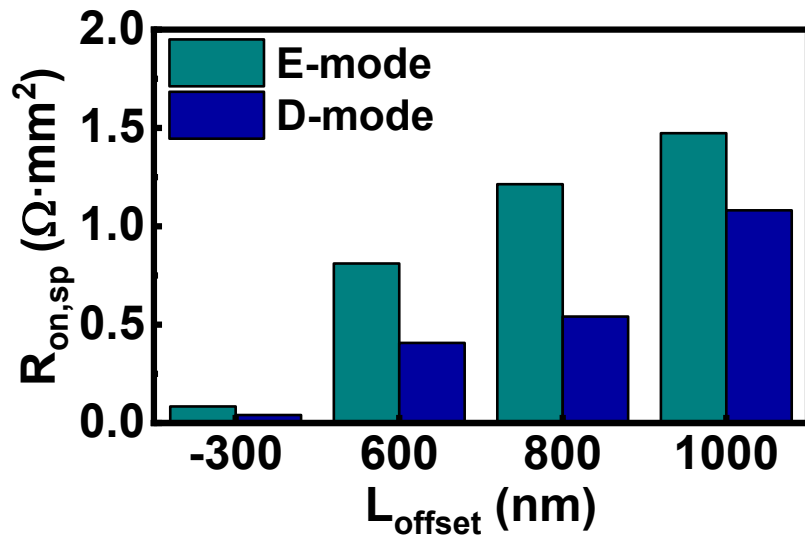
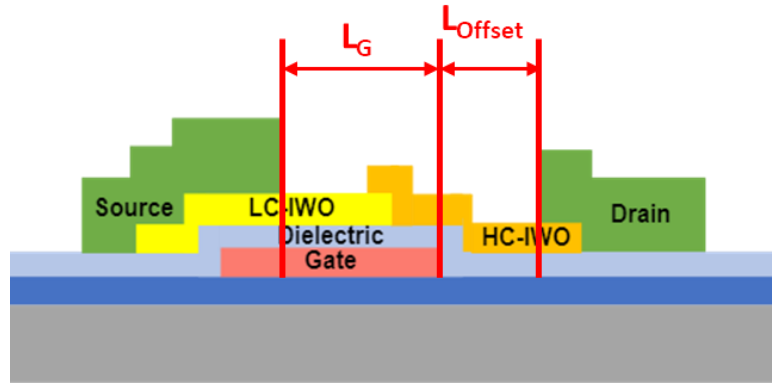


D-mode ($L_G = 600$ nm)

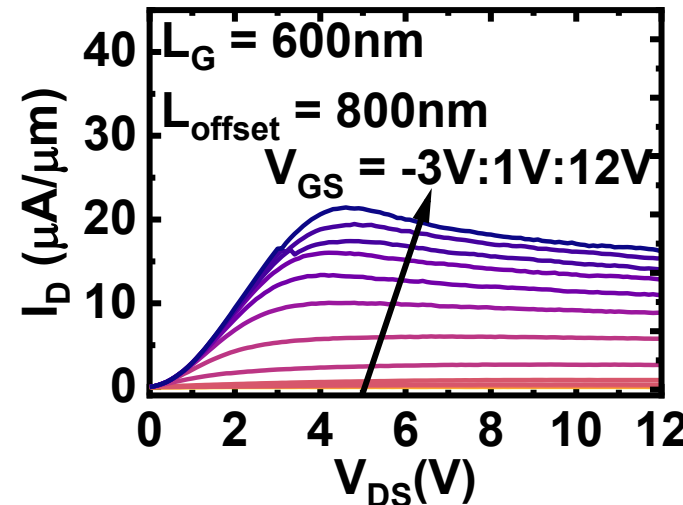


- The E-mode power FETs have a positive V_{TH} ($=1.1$ V @ $L_{offset} = 800$ nm) and the D-mode power FETs show a negative V_{TH} ($=-1.7$ V @ $L_{offset} = 800$ nm).

Specific On-Resistance



E-mode

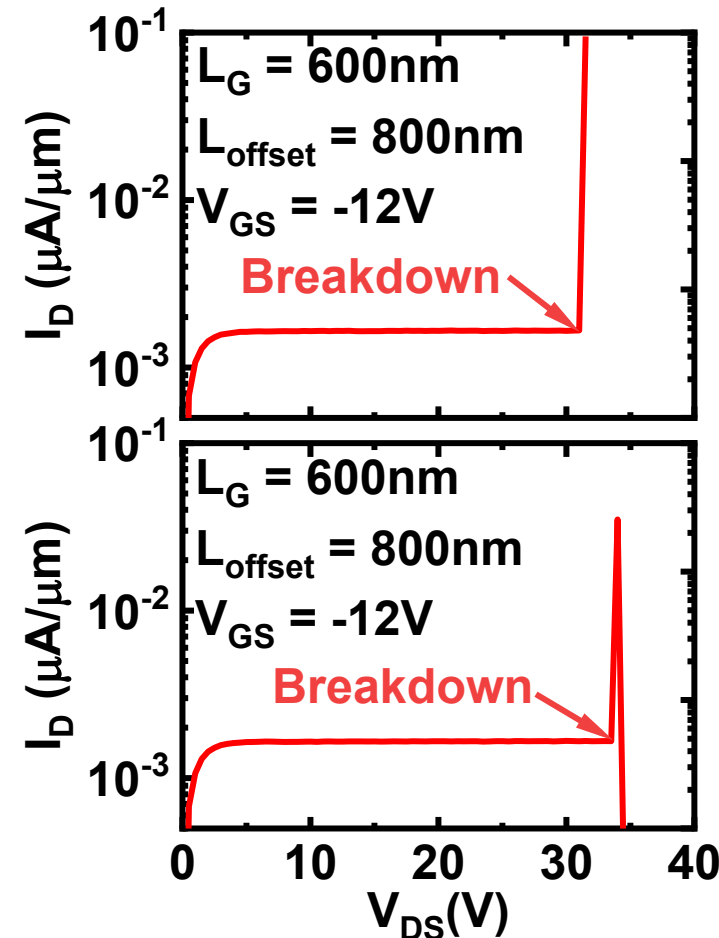
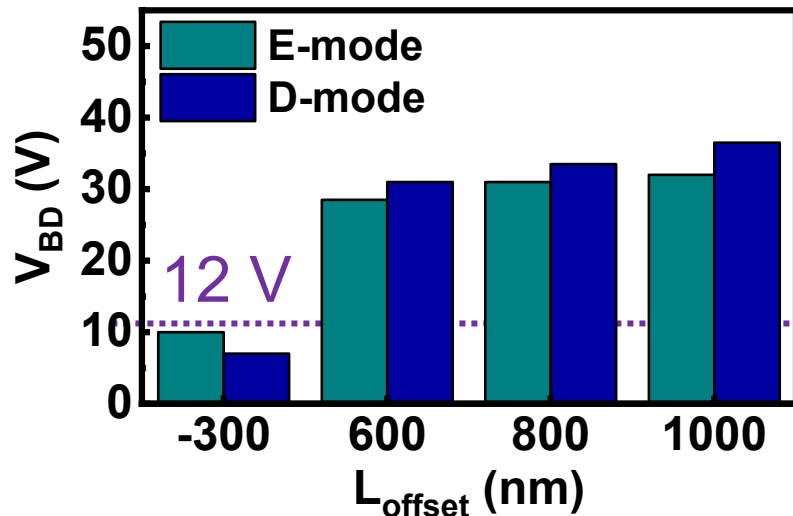
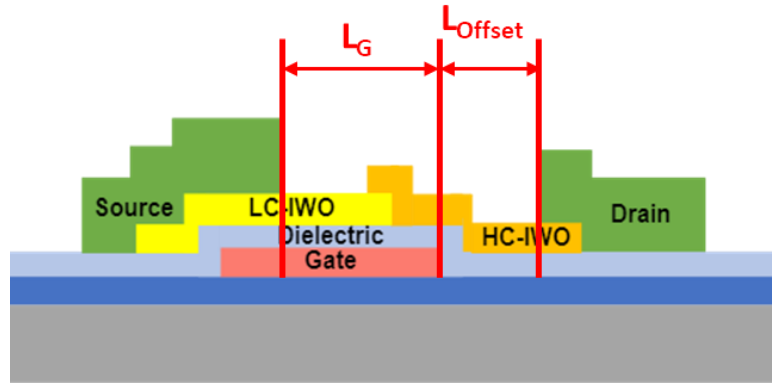


D-mode

➤ The power FETs show $>10x$ larger $R_{\text{on,sp}}$ than the conventional MOSFETs.

➤ 1.7x increase in L_{offset} leads to 1.8x (E) and 2.6x (D) increase in $R_{\text{on,sp}}$.

Drain Breakdown Voltage

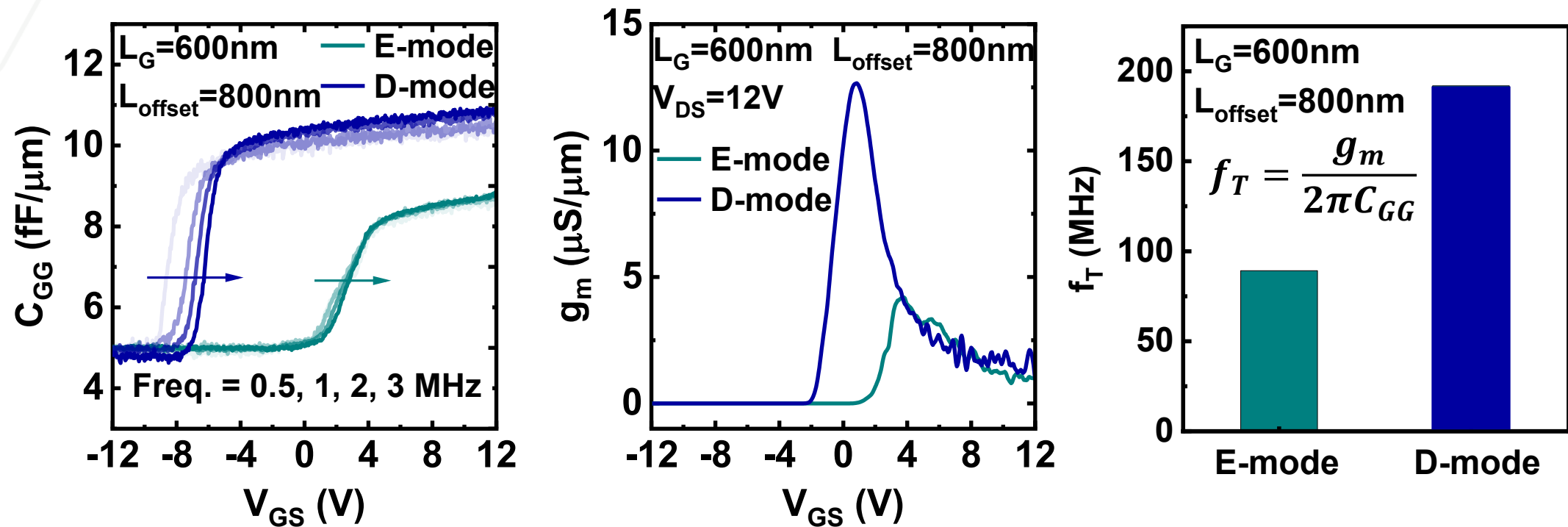


E-mode

D-mode

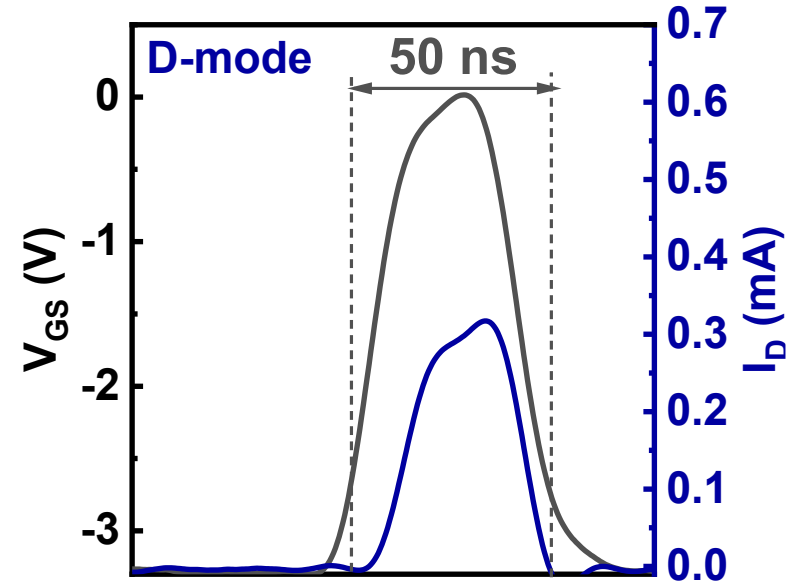
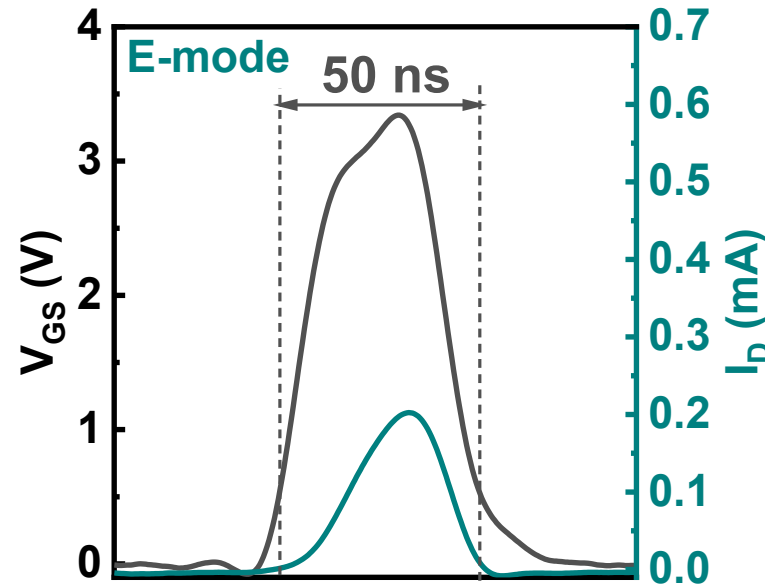
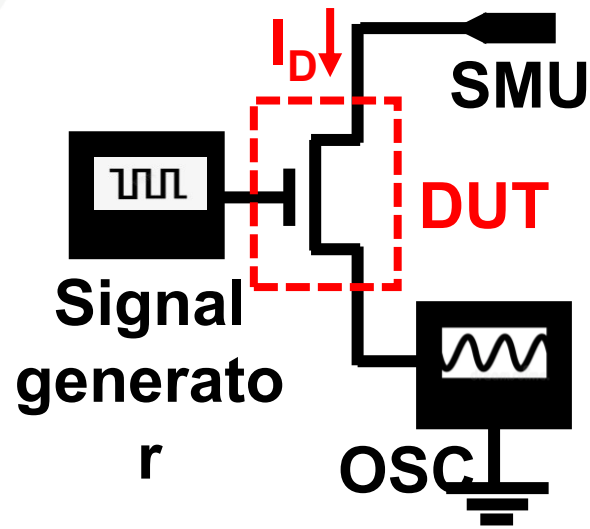
- The power FETs show a off-state drain V_{BD} of >12 V, which is >3 x higher than the conventional MOSFETs.
- Tradeoff: 3-4x increase in V_{BD} for ~ 14 x increase in $R_{\text{on,sp}}$.

Switching Characteristics



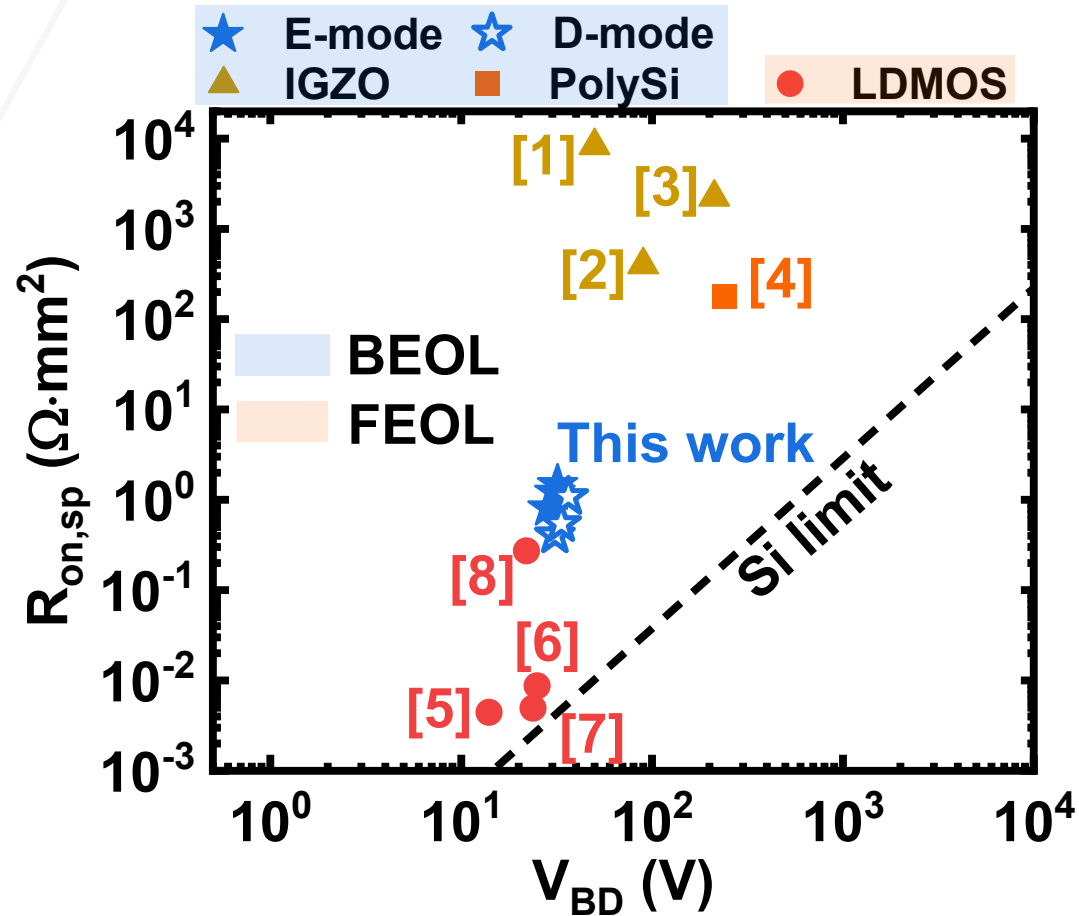
- E- and D-mode devices ($L_{\text{offset}} = 800\text{ nm}$) exhibit an estimated switching frequency f_T of 90 MHz and 192 MHz, respectively.

Pulse Response



- Both devices (at $V_{DS}=12$ V) can respond to the 50-ns-wide input gate pulses.

Benchmarking of BEOL Compatible Power FETs



- IWO power FETs show >1000x reduction in $R_{on,sp}$ compared with other BEOL-compatible power FETs.
- LDMOS with similar V_{BD} have lower $R_{on,sp}$, but this technology is BEOL incompatible.

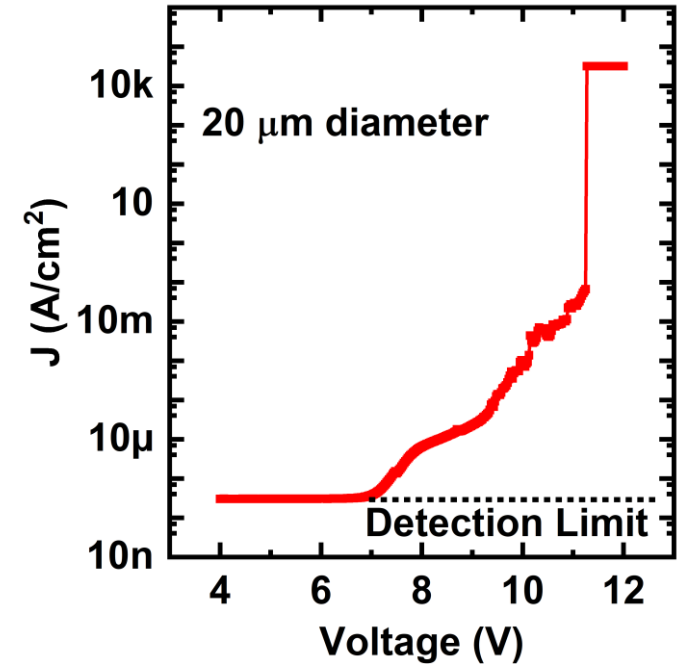
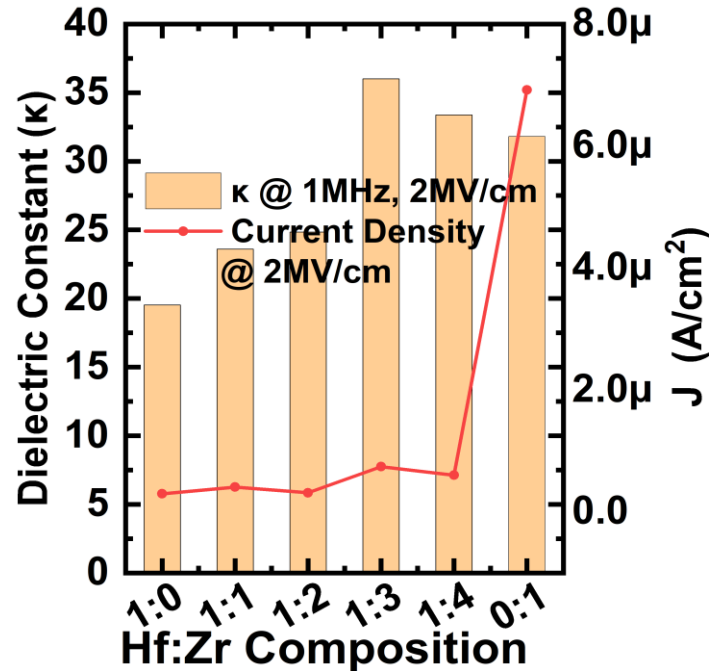
[1] G. Yang, et al., TED 2021. [2] C. Park, et al., EDL 2021. [3] H. Huo, et al., Semicond Sci Tech 2021. [4] H.C. Cheng, et al., J. Electrochem. Soc. 2004. [5] P.Y. Huang, et al., ISPSD 2014. [6] H. Lin, et al., VLSI 2021. [7] S.Y. Chen, et al., TED 2021. [8] A. Houadef, et al., Eng. Proc. 2022.

On-chip Superlattice MIM Capacitors

$\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ Al_2O_3 $\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ Al_2O_3 $\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ Al_2O_3 $\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$
 superlattice stack

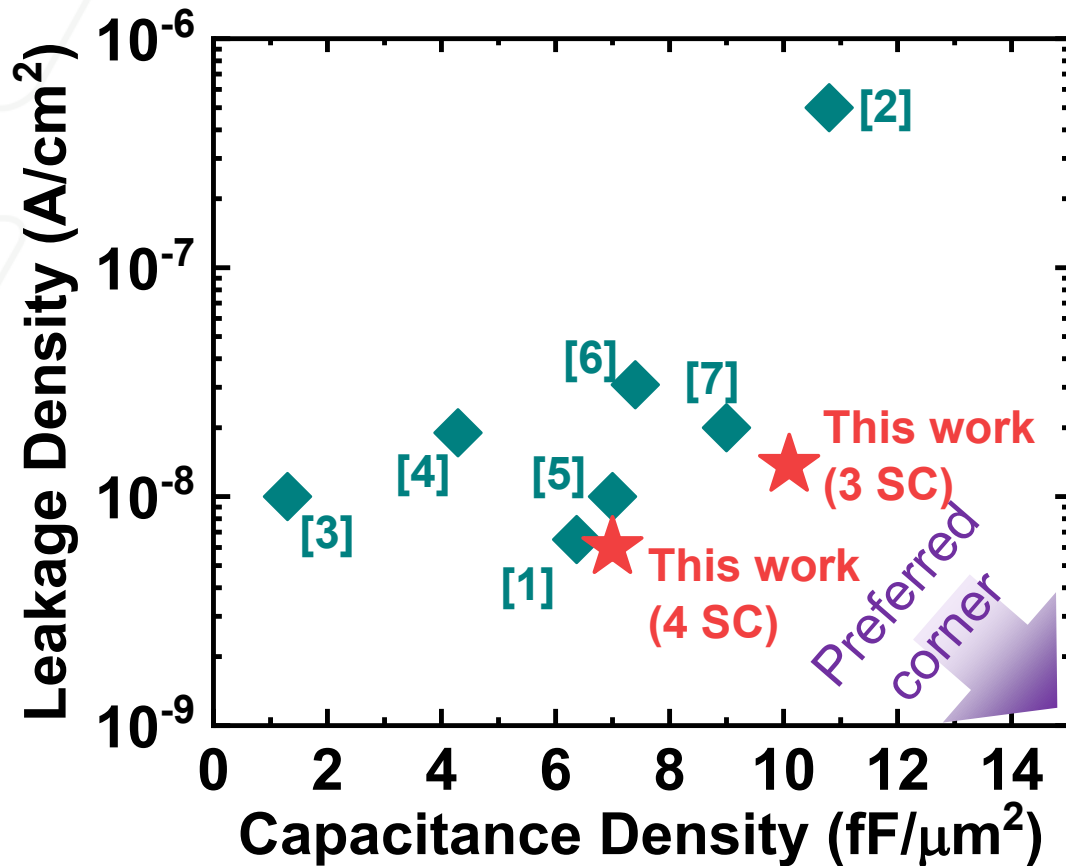
TiN 20 nm
$\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ (HfO_2 1 cyc + ZrO_2 3 cyc) x 30
Al_2O_3 (10 cyc)
$\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ (HfO_2 1 cyc + ZrO_2 3 cyc) x 30
Al_2O_3 (10 cyc)
$\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ (HfO_2 1 cyc + ZrO_2 3 cyc) x 30
TiN 20 nm

~27.6 nm



- $\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ superlattice laminate: improve dielectric constant.
- Al_2O_3 interlayer: suppress m-phase formation and limit leakage in thicker superlattice stacks.

Benchmarking of On-Chip Planar Superlattice MIM Capacitors for High-Voltage Applications

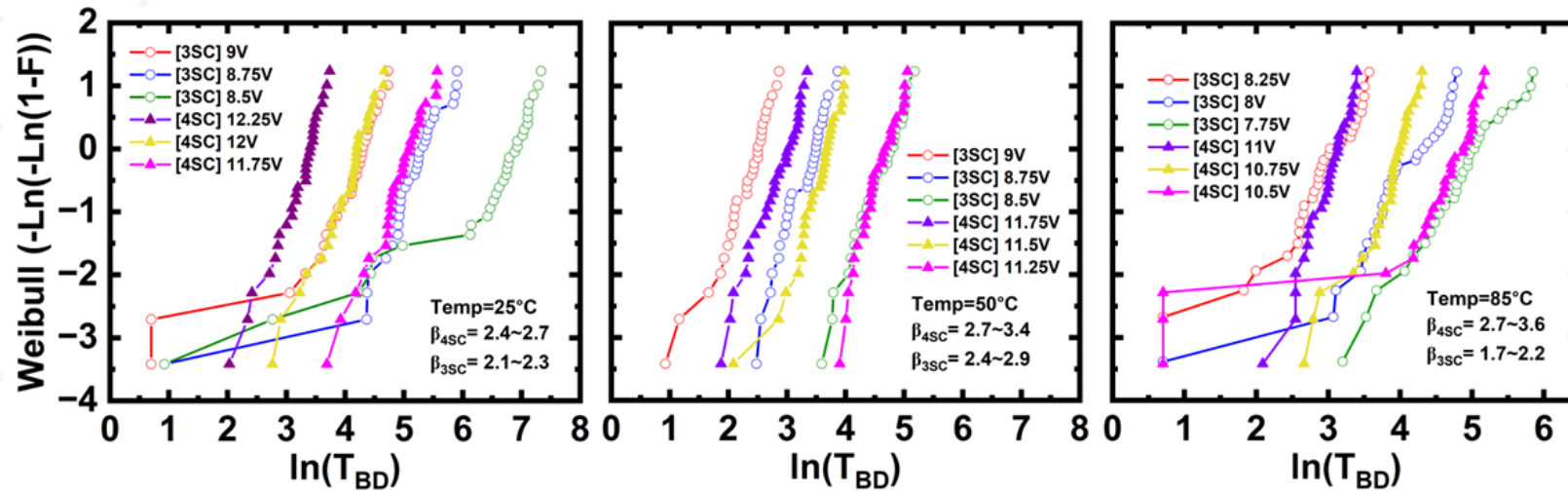


- >34x reduction in leakage current with a high capacitance density (>10 fF/μm²).
- V_{BD} withstands the max. DC voltage stress for 2:1 step-down conversion from 12 V.

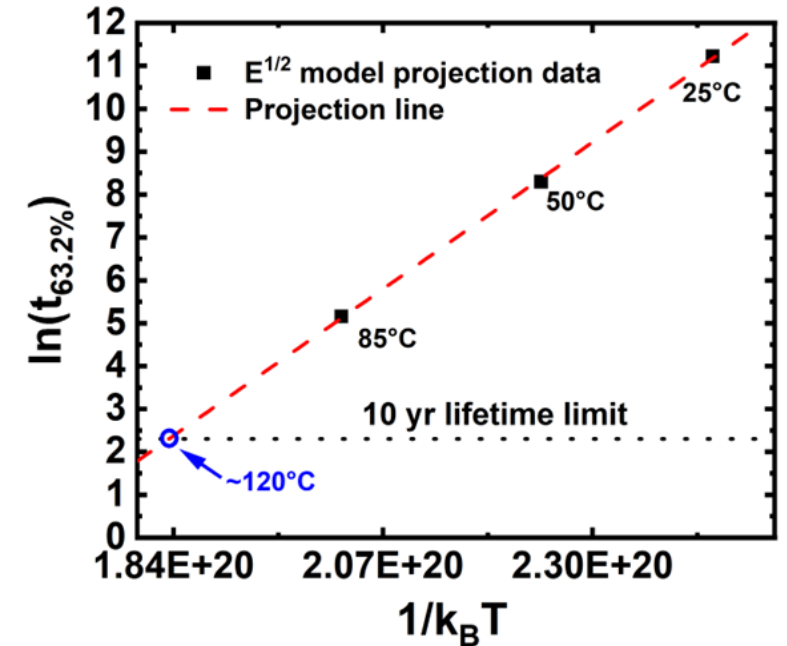
[1] H. Lin, et al., TVLSI 2022. [2] C. Fang, et al., EDL 2019. [3] G. Hellings, et al., VLSI 2015. [4] W. S. Liao, et al. IEDM 2014. [5] J. Kim, IEEE 3DIC 2015. [6] Q. -X. Zhang, et al. EDL 2014. [7] L. Zhang, et al. EDL 2009.

Reliability of High-Voltage On-Chip Superlattice MIM Capacitors

Weibull distribution at different temps.

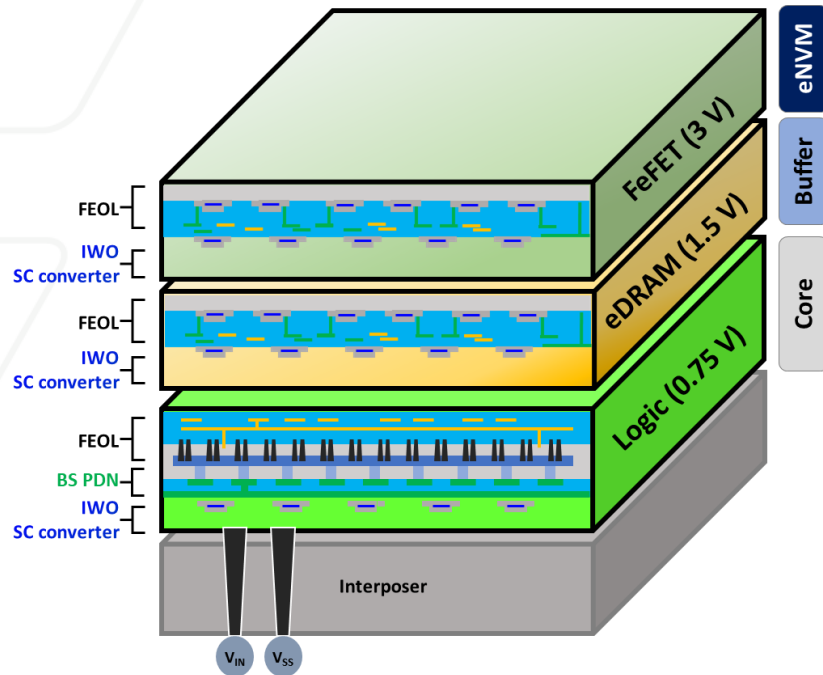


Lifetime projection



- Poole-Frenkel conduction ($\ln(J) \propto \sqrt{E}$) dominates at 6 V.
- Projected lifetime of ~ 10 years at 6 V, 120°C ensures reliable on-chip voltage conversion from 12 V to 6 V.

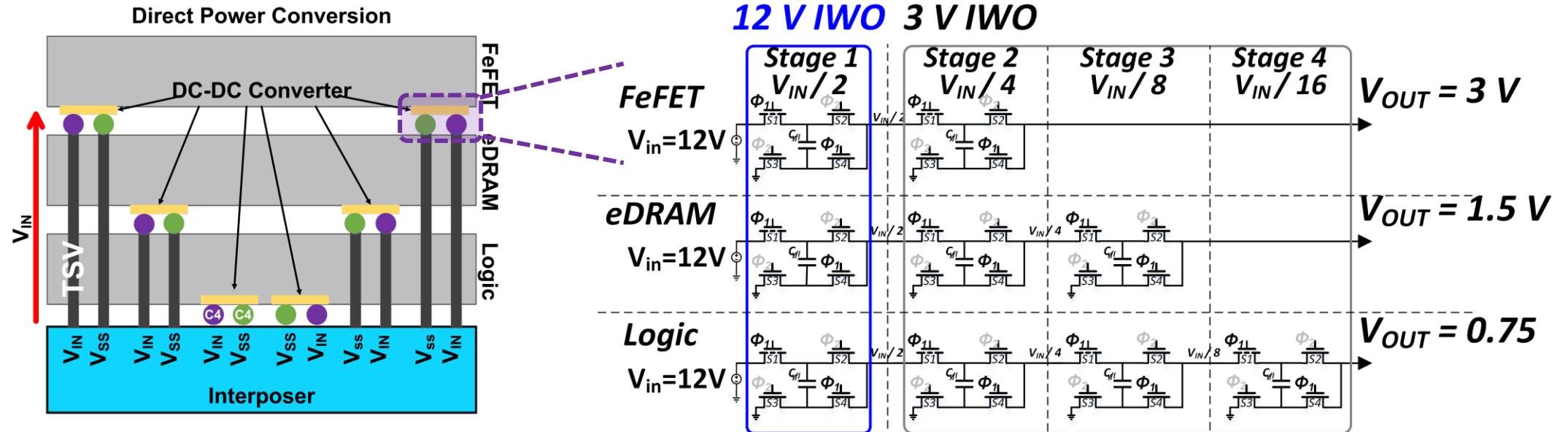
H3D Integrated Transformer Accelerator using On-Chip SC DC-DC Converters



Tier	FeFET	eDRAM	Logic
Application	Weight memory	Global buffer	self-attention & other kernel computing
Technology Node	22 nm	7 nm	2 nm
Device	IWO	IWO	CMOS
Supply voltage	3 V	1.5 V	0.75 V
Area	810.8 mm ²	817.9 mm ²	*719.2 mm ²
Bonding	Face-down	Face-down	Face-up
BEOL Power delivery	Front-side	Front-side	Back-side
Power density	1 mW/mm ²	4 mW/mm ²	*137.8 mW/mm ²
Capacity	8 GB	16 GB	-

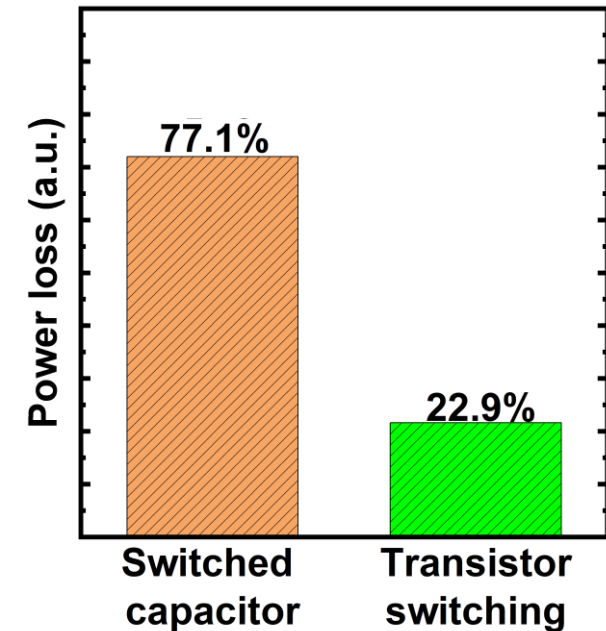
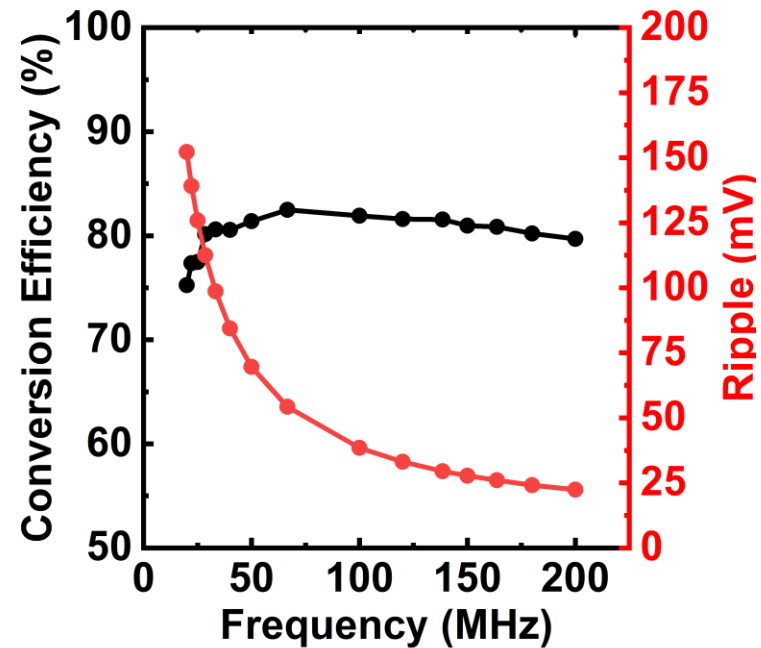
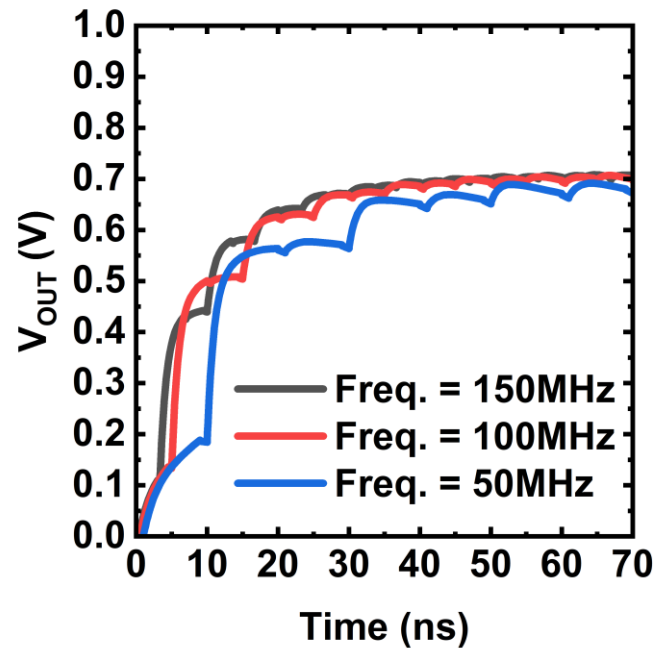
- On-chip SC DC-DC converters are used to efficiently convert input voltage at the interposer level to the lower supply voltage domains required in each tier.

Multi-Stage On-Chip SC DC-DC Converters



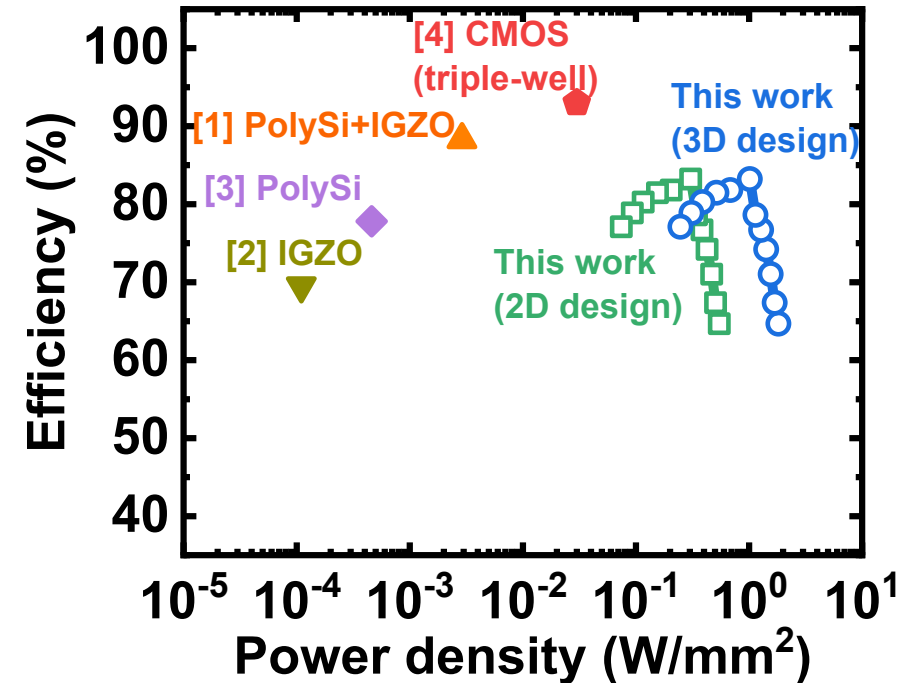
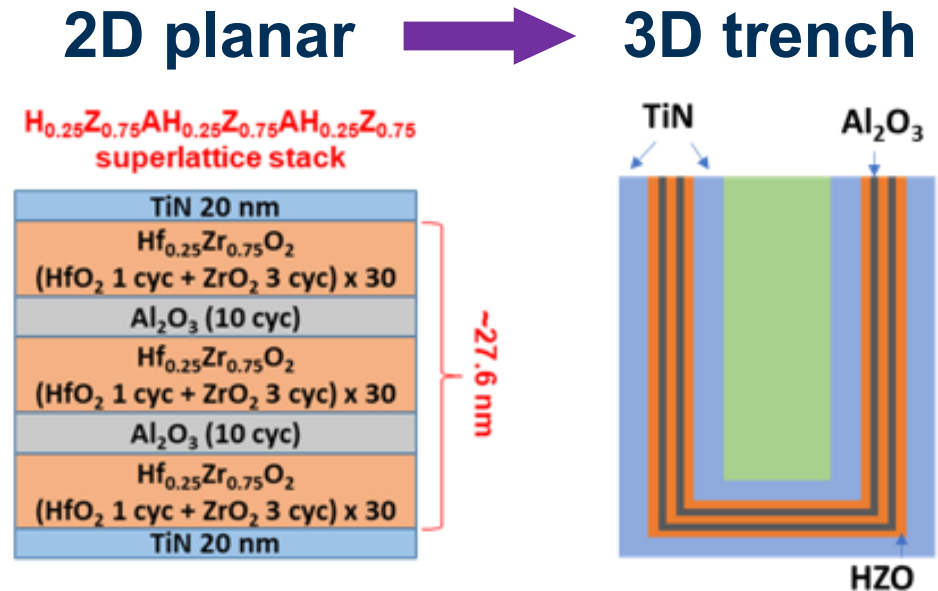
- Input voltage directly delivered from the interposer to each tier in parallel.
- In each tier, cascaded unit SC DC-DC converters provide the desired supply voltages by multi-stage conversion.

SPICE Simulation on Voltage Conversion



- The converters achieve ~83% efficiency (with a reasonable voltage ripple of 38 mV).
- Intrinsic loss is 3.4x higher than switching loss .

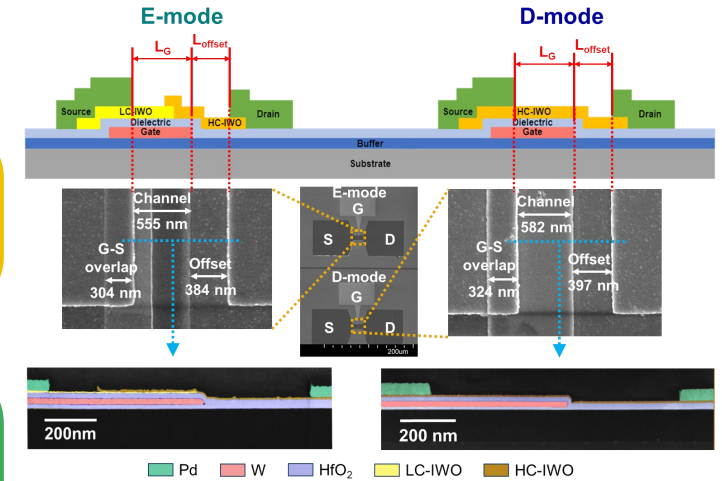
Design Optimization and Benchmarking



- Transition from 2D planar to 3D trench flying capacitors shows 3.3× increase in power density.
- Potentially competitive against SOTA FEOL-compatible technologies.

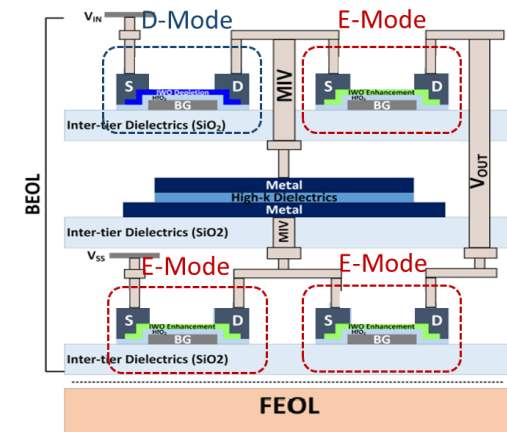
Summary

- Demonstrated the BEOL-compatible IWO power FETs with a drain V_{BD} of >12 V and a f_T of 192 MHz.
- Developed both E- and D-mode IWO power FETs, which could be co-integrated on the same chip.
- Demonstrated high-density high-voltage on-chip superlattice MIM capacitors with a projected lifetime of ~ 10 years at 120°C and 6 V.
- Analyzed the performance of on-chip SC DC-DC converters showcasing a high efficiency of $\sim 83\%$ for H3D integrated transformer accelerators.



$\text{H}_{0.25}\text{Zr}_{0.75}\text{AlH}_{0.25}\text{Zr}_{0.75}\text{AlH}_{0.25}\text{Zr}_{0.75}$
superlattice stack

TiN 20 nm	-27.6 nm
$\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ (HfO_2 1 cyc + ZrO_2 3 cyc) x 30	
Al_2O_3 (10 cyc)	
$\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ (HfO_2 1 cyc + ZrO_2 3 cyc) x 30	
Al_2O_3 (10 cyc)	
$\text{Hf}_{0.25}\text{Zr}_{0.75}\text{O}_2$ (HfO_2 1 cyc + ZrO_2 3 cyc) x 30	
TiN 20 nm	



Acknowledgment



Semiconductor
Research
Corporation



CHIMES

Center for Heterogeneous Integration
of Micro Electronic Systems

Thank you all for your attention

Dr. Sunbin Deng

Email: sdeng76@gatech.edu